



Patent

Attorney Docket No. 8003-398

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application)
Inventor(s): Emir Gurer et al.)
Application No: 09/874,073)
Filed: June 4, 2001)
Title: Plasma Deposition of Spin Chucks to Reduce)
Contamination of Silicon Wafers)

Patent Application

Art Unit: 1763

Examiner: Kackar, Ram N.

Mail Stop Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENT

Introductory Comments:

This Amendment is in response to the Office Action dated December 31, 2002.

Reconsideration is respectfully requested in view of the following amendments and remarks.